CLAIMS

1. – 15 (canceled)

A3

16. (currently amended) A method for transporting wafers from a first processing tool assigned to a first bay to a second processing tool assigned to a second bay, comprising the following steps:
   - transferring said wafers from said first processing tool to at least one first intra-bay pod;
   - transporting said at least one intra-bay pod to a first stationary storage system comprising a first buffer for storing a plurality of wafers out of pods;
   - transferring said wafers into said first buffer via a first load-and-unload station;
   - reading information from the wafers and labeling the wafers in the first buffer;
   - transferring said wafers from said first buffer to at least one pod;
   - transporting said at least one pod to a second stationary storage system comprising a second buffer for storing a plurality of wafers out of pods;
   - transferring said wafers from said at least one pod into said second buffer;
   - reading information from the wafers and labeling the wafers in the second buffer;
   - transferring said wafers from said second buffer to at least one second intra-bay pod;
   - transporting said at least one second intra-bay pod to said second processing tool; and
   - transferring said wafers from said at least one second intra-bay pod to said second processing tool.

17. (original) The method according to claim 16, further comprising the step of transferring said wafers from said first stationary storage system to said second stationary storage system where the first stationary storage system reaches capacity.

18. (new) The method of claim 16, wherein labeling comprises lot identification.

19. (new) The method of claim 16, wherein reading comprises processing status.

20. (new) The method of claim 16, wherein labeling comprises wafer identification.

3